

Flavio Giacomozzi graduated in Mechanical Engineering at the University of Padova. In 1983 joined former ITC-IRST, now Fondazione Bruno Kessler (FBK), where he was first involved in the improvements of surface properties of materials by thin film deposition and ion implantation. He contributed to the realization of the microfabrication facility and the development of fabrication processes. Since 1996, he is working mainly on the development of MEMS technologies for the realization of different kinds of devices, for both research and industrial projects, like sensors, capacitive microphones, RF MEMS switches and complex circuits, microfluidic devices. He is author or co-author of numerous publications in the field of MEMS.